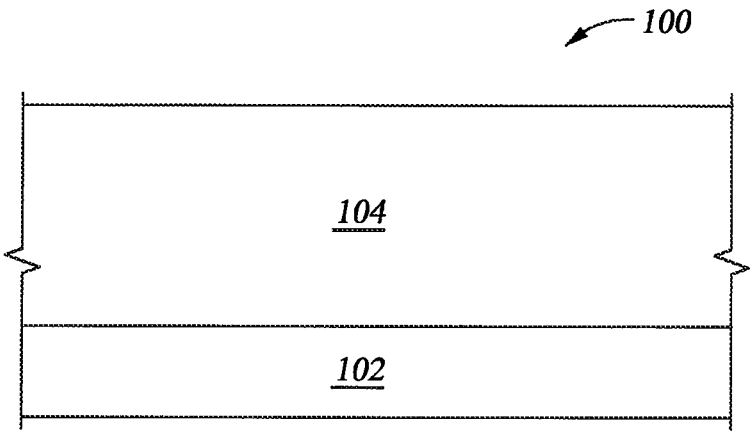
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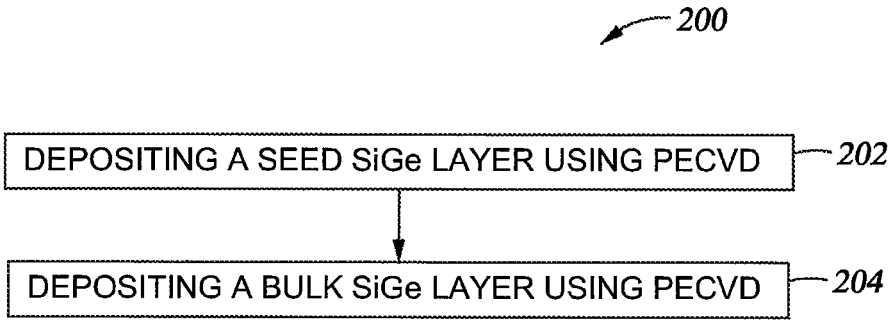
104
102

Fig. 1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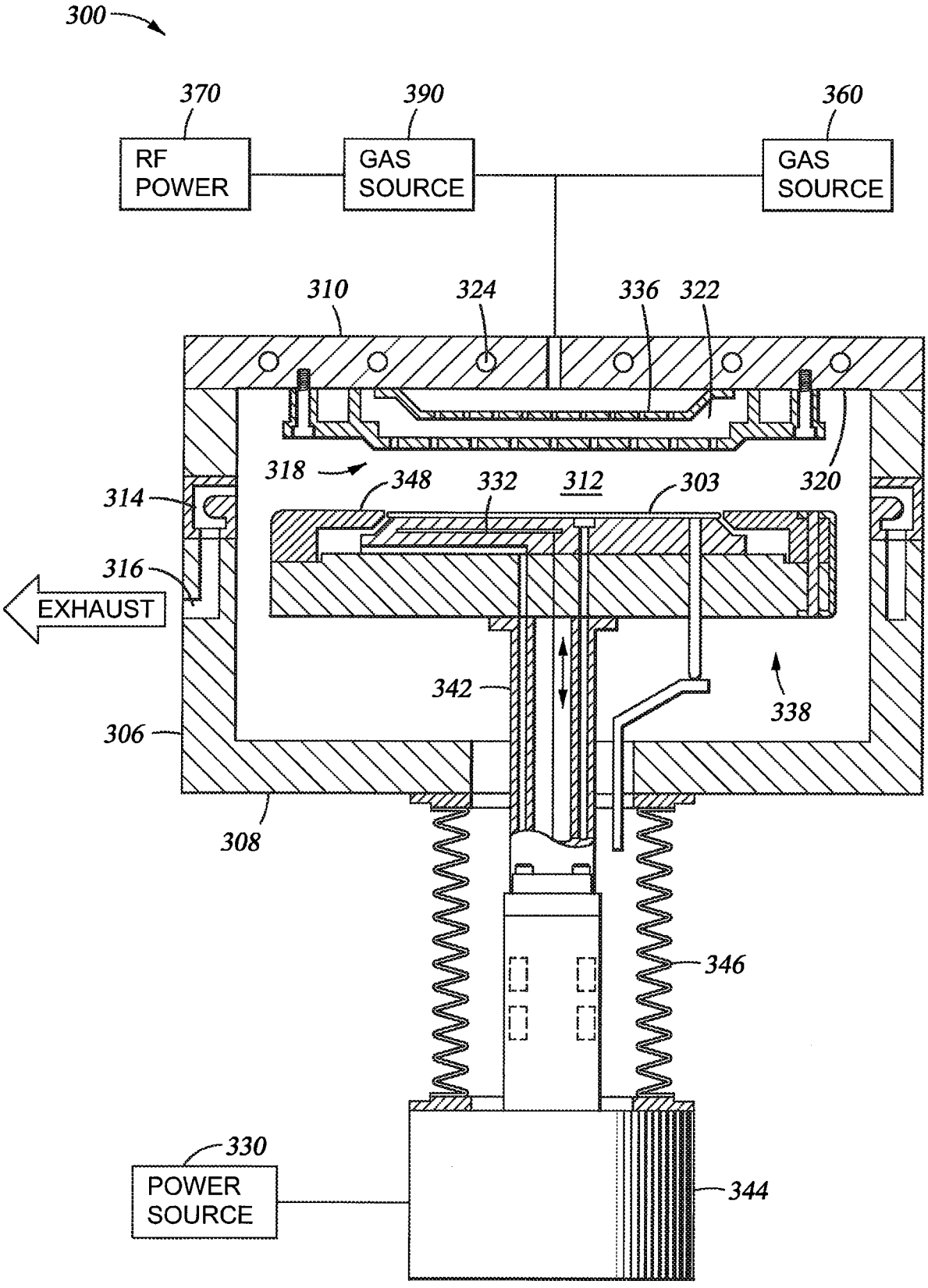
DEPOSITING A SEED SiGe LAYER USING PECVD
202
DEPOSITING A BULK SiGe LAYER USING PECVD
204

Fig. 2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RF POWER
390
GAS SOURCE
360
GAS SOURCE
310
324
336
322
318
348
332
312
303
320
314
316
EXHAUST
342
338
306
308
346
330
POWER SOURCE
344

Fig. 3